

Notice of References Cited	Application/Control No. 10/018,413	Applicant(s)/Patent Under Reexamination RAISANEN, HEIKKI	
	Examiner Paul D Kim	Art Unit 3729	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,912,759	06-1999	Good et al.	359/297
	B	US-4,654,546	03-1987	Kirjavainen, Kari	307/400
	C	US-4,370,182	01-1983	Becker et al.	156/52
	D	US-3,943,614	03-1976	Yoshikawa et al.	29/25.35
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 59230123 A				
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Characterization of monolithic n-type 6H-SiC piezoresistive sensing elements"; Shor, J.S.; Bemis, L.; Kurtz, A.D.; Electron Devices, IEEE Transactions on Volume 41, Issue 5, May 1994 Pages:661 - 665.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.